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Anand Krishna Asundi
Huijie Zhao
Wolfgang Osten
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Introduction

Applied Optics and Photonics China (AOPC2017) is the annual conference of the CSOE, and one of the largest academic and industry activities in the field of optical and optoelectronic technology in China. The organization committee has built a platform of academic exchanges, industry exhibitions, and cooperation negotiations in one. There are 8 technical conferences, 7 themes of the Exhibition and approximately 600 technical presentations. We sincerely hope that the research and development of optoelectronic technology are promoted, and the international cooperation between industry and the optical and optoelectronic fields are enhanced.

AOPC2017 is technically co-sponsored by the Chinese Society for Optical Engineering, the Optical Society of Korea (OSK), Optics and Photonics Society of Singapore (OPSS), European Optical Society (EOS), Optical Society of Japan (OSJ) and SPIE. There are also 60 cooperative organizers to support the conference. We received over 1209 contributions from more than 15 countries, including the United States, the United Kingdom, Germany, France, Spain, Australia, Canada, Mexico, Brazil, Japan, Korea, Thailand, Singapore, the Russian Federation, China, and more. There are more than 700 presentations published in the Proceedings of SPIE. After careful discussion, we suggested four keynote speeches which are presented by famous scientists from Germany, Australia, Japan and China. 138 excellent invited talks were presented, 45 are from outside of China. Their presentations reflect first-class research in the field of optics and photonics technology. On behalf of the Organization Committee of AOPC, I express thanks to all the invited speakers and authors for their contributions and support of the conference.

Finally, on behalf of Prof. Zhuang Songlin, and other co-chairmen, and the Organization Committee of AOPC, I would like to heartily thank our sponsors and cooperating organizers for all they have done for the conference, the participants and friends for their interests and efforts in helping us to make the conference a success, the program committee for their effective work and valuable advice, and especially the AOPC2017 Secretariat and the staff of SPIE for their tireless effort and outstanding services in preparing the conference and publishing the Proceedings.

We wish AOPC2017 great success! Hope to see you next year!

Guofan Jin